

Monte Carlo Simulations of Electrons in Al₄SiC₄ Ternary Carbide

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An Al₄SiC₄ ternary carbide has become a promising wide band-gap semiconductor for the semiconductor industry over the last decade because of its emerging properties [1]. A crystal structure of Al₄SiC₄ is illustrated in Fig. 1. The Al₄SiC₄ band-gap has been calculated to be 2.48 eV [2,3] thus opening a possibility for the design of carbide heterostructure devices in a combination with 4H-SiC or 3C-SiC. These heterostructure carbide devices could potentially resolve issues with the large interface density of states at the semiconductor interface with a dielectric layer leading to a low inversion carrier mobility in SiC MOSFETs [4]. Other remarkable properties include superior oxidation resistance [5], superior wear resistance, low weight, high strength, and high thermal conductivity [6].

In this work, an ensemble Monte Carlo (MC) simulation code is developed to investigate the electron transport in bulk Al₄SiC₄. Al₄SiC₄ has a wurzite lattice [2,3] as shown in Fig. 2. We assume that the two lowest valleys will play a role in electron transport. The *M*-valley has also six locations contributing one-half (a total of 3 equivalent valleys). The *K*-valley has six locations contributing one-third to the 1st Brillouin zone (a total of 2) as shown in Figs. 3 and 4. Therefore, a two-valley non-parabolic anisotropic bandstructure model is employed with the *M*-valley to be a minimum and the second *K*-valley to be 0.52 eV above as illustrated in Fig. 5. The electron interactions with polar and non-polar phonons within and between *M*- and *K*-valleys are listed in Table 1. The material parameters in Table 2 use a mix of experimental and theoretical sources like optical phonon energies extracted from IR/Raman spectroscopy [3].

Valley	Transition	Scattering Type
<i>M</i> ₁	<i>M</i> ₁ → <i>M</i> ₁	Intra Polar
	<i>M</i> ₁ → <i>M</i> _{2,3}	Inter Non-Polar
	<i>M</i> ₁ → <i>K</i>	Inter Non-Polar
<i>M</i> ₂	<i>M</i> ₂ → <i>M</i> ₂	Intra Polar
	<i>M</i> ₂ → <i>M</i> _{1,3}	Inter Non-Polar
	<i>M</i> ₂ → <i>K</i>	Inter Non-Polar
<i>M</i> ₃	<i>M</i> ₃ → <i>M</i> ₃	Intra Polar
	<i>M</i> ₃ → <i>M</i> _{1,2}	Inter Non-Polar
	<i>M</i> ₃ → <i>K</i>	Inter Non-Polar
<i>K</i>	<i>K</i> → <i>M</i> ₁	Inter Non-Polar
	<i>K</i> → <i>M</i> ₂	Inter Non-Polar
	<i>K</i> → <i>M</i> ₃	Inter Non-Polar

Table 1: Electron-phonon scattering transitions considered in the MC model.

Finally, *M*-valley *k*-vector (inverse) transformations to a spherical space (denoted by *) within the anisotropic analyt-

Table 2: Al₄SiC₄ material parameters considered in the MC simulations.

Parameter [Unit]	Value
Mass Density [g/cm ³]	3.03 ^a
Lattice Const. [Å]	3.28 ^a
Piezoelectric Const. [C/m ²]	0.47 ^a
Longitudinal Acoustic Velo. [m/s]	10577 ^a
Transverse Acoustic Velo. [m/s]	6431 ^a
Polar Opt. Phon. Energy [meV]	67.32 ^b , 107.24 ^b
Non-Polar Opt. Phon. Energy [meV]	85.55 ^b
Acoustic Def. Potential [eV]	11.4 ^c
Indirect Band Gap for the <i>M</i> -valley	$E_G^{(M)} = 2.78$
(<i>M</i>) & the <i>K</i> -valley (<i>K</i>) [eV]	$E_G^{(K)} = 3.30$ ^a
Electron Effective Masses [<i>m</i> _e]	$m_l^{*(M)} = 0.568$ ^d
	$m_t^{*(M)} = 0.695$ ^d
	$m_l^{*(K)} = 1.057$ ^d
	$m_t^{*(K)} = 0.936$ ^d

^aRef. [2]. ^bRef. [3]. ^cAverage taken from [7]. ^dExtracted value from DFT calculations [2]. *m*_e is the rest mass of an electron.

ical model use a combination of Herring-Vogt and rotational transformations [8] as:

$$k_x^*(k_x) = k_x(k_x^*)\cos(\theta) - (+)k_y(k_x^*)\sin(\theta) \quad (1)$$

$$k_y^*(k_y) = k_y(k_y^*)\cos(\theta) + (-)k_x(k_y^*)\sin(\theta) \quad (2)$$

$$k_z^*(k_z) = k_z(k_z^*) \quad (3)$$

The MC simulations in Figs. 6 and 7 predict that Al₄SiC₄ will have a maximum electron drift velocity of 1.35×10^7 cm s⁻¹ at an electric field of 1400 kV cm⁻¹ and a maximum electron mobility of 82.9 cm²V⁻¹s⁻¹. Fig. 8 shows the electron mobility dependence on ionized impurity concentration. The average electron kinetic energy and valley occupation are plotted in Figs. 9 and 10, respectively.

References

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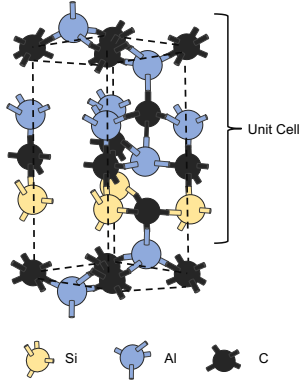


Fig. 1: A crystal structure of Al_4SiC_4 . The blue, yellow, and black spheres represent Al, Si, and C atoms, respectively.

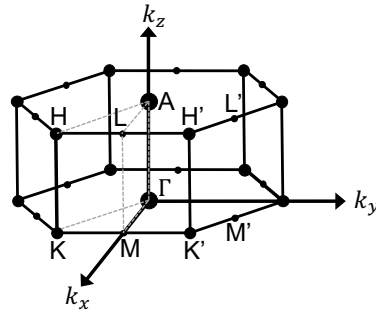


Fig. 2: A schematic of hexagonal bandstructure of Al_4SiC_4 in the k -space showing a location of principal valleys.

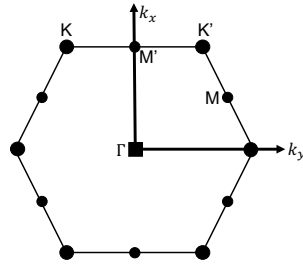


Fig. 3: The hexagonal (0001) $k_x - k_y$ plane of Al_4SiC_4 showing a location of principal valleys.

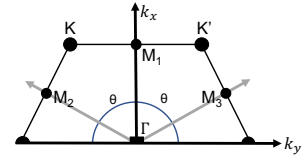


Fig. 4: Detail of locations of the M -valleys in the (0001) plane within the Al_4SiC_4 hexagonal structure, where $\theta = \pm 60^\circ$ or $\pi/3$.

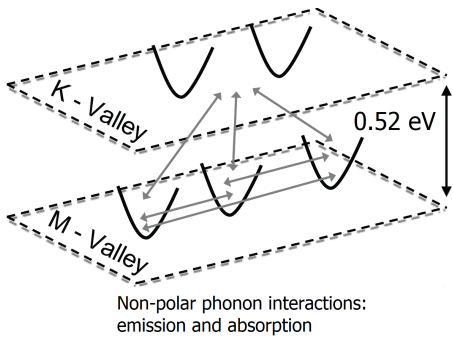


Fig. 5: A schematic of conduction band minimum valleys for Al_4SiC_4 showing details of the number of equivalent M - and K - valleys, the separation between valleys, and the electron—non-polar phonon interactions considered in the transport model.

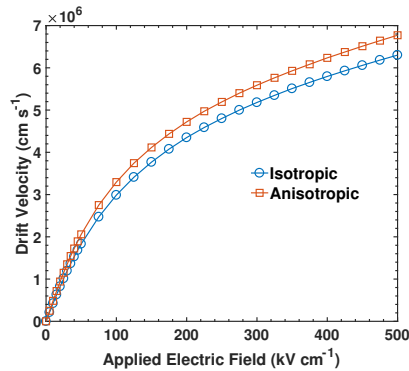


Fig. 6: Electron drift velocity as a function of applied electric field in a bulk Al_4SiC_4 . The velocity obtained assuming an anisotropic (red squares) and a simpler isotropic (blue circles) bandstructure are shown.

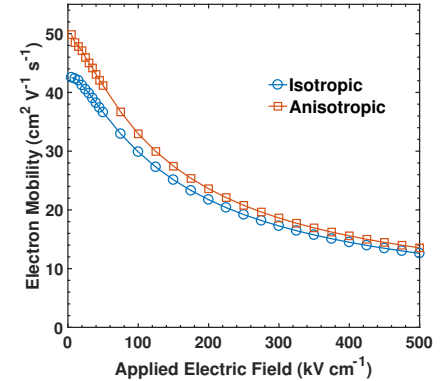


Fig. 7: Electron mobility as a function of applied electric field in a bulk Al_4SiC_4 . The mobility obtained assuming an anisotropic (red squares) and a simpler isotropic (blue circles) bandstructure are plotted.

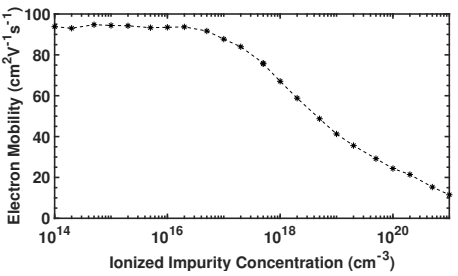


Fig. 8: Electron mobility as a function of ionized impurity concentration in a bulk Al_4SiC_4 .

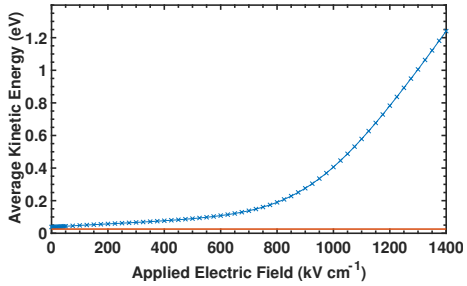


Fig. 9: Average kinetic energy as a function of applied electric field in a bulk Al_4SiC_4 .

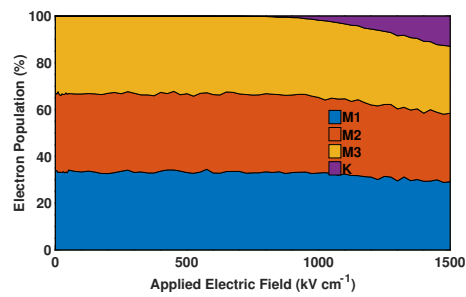


Fig. 10: Valley occupancy of electrons in the M - and K -valleys vs. applied electric field in bulk Al_4SiC_4 .